

ELECTRON-BEAM DEVICE AND DETECTOR SYSTEM

Abstract of the Disclosure

An electron-beam device having a beam generator for generating an electron beam, an
5 objective lens for focusing the electron beam on an object, and at least one detector for
detecting electrons scattered on the object or emitted by the object. Furthermore, a
detector system for detecting electrons is described. With an electron-beam device
having a detector system according to the present invention, it is possible to make a
selection in a simple manner, in particular according to backscattered and secondary
10 electrons. At the same time, as many electrons as possible may be detected using the
detector system. For this purpose, the electron-beam device exhibits at least one
adjustable diaphragm which is allocated to the detector. The detector system exhibits a
detector on which a reflector for reflecting electrons onto the detector is accommodated.

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